IN THE CLAIMS:

Claims 1-20. (canceled)

21. (New) An ink jet recording head formed by a method comprising:

forming a first electrode layer on a diaphragm;

forming a piezoelectric layer on the first electrode layer;

forming a second electrode layer on the piezoelectric layer; and

etching completely through the second electrode layer, the piezoelectric layer, and the first electrode layer so that a portion of the diaphragm is exposed.

22. (New) The ink jet recording head according to claim 21, wherein the diaphragm is attached to a substrate.

23. (New) The ink jet recording head according to claim 22, wherein a nozzle plate is attached to the substrate.

24. (New) The ink jet recording head according to claim 23, wherein the nozzle plate is formed with a nozzle orifice.

25. (New) A method of manufacturing an ink jet recording head, the method comprising:

forming a first electrode layer on a diaphragm;

forming a piezoelectric layer on the first electrode layer;

forming a second electrode layer on the piezoelectric layer; and

etching completely through the second electrode layer, the piezoelectric layer, and the first electrode layer so that a portion of the diaphragm is exposed.

26. (New) The method according to claim 25, further comprising attaching the diaphragm to a substrate.

27. (New) The method according to claim 26, further comprising attaching a nozzle plate to the substrate.

28. (New) The method according to claim 27, forming a nozzle orifice in the nozzle plate.

29. (New) The method according to claim 25, wherein only a single mask material is used to pattern the second electrode layer, the piezoelectric layer, and the first electrode layer during the etching step.

30. (New) An ink jet recording head formed by a method comprising:

forming a first electrode layer on a diaphragm;

forming a piezoelectric layer on the first electrode layer;

forming a second electrode layer on the piezoelectric layer; and

etching completely through at least the second electrode layer and the piezoelectric layer so that a portion of the diaphragm is exposed.

31. (New) The ink jet recording head according to claim 30, wherein the diaphragm is attached to a substrate.

32. (New) The ink jet recording head according to claim 31, wherein a nozzle plate is attached to the substrate.

33. (New) The ink jet recording head according to claim 32, wherein the nozzle plate is formed with a nozzle orifice.